

**AMENDMENTS TO THE SPECIFICATION**

**On page 1, beginning with “Description” and ending with “...such lithography objective”, please replace the present title with the following amended title:**

LITHOGRAPHY LENS SYSTEM AND PROJECTION EXPOSURE SYSTEM PROVIDED  
WITH AT LEAST ONE LITHOGRAPHY LENS SYSTEM OF THIS TYPE

**Amend the specification by adding before the first line the sentence:**

This application is a National Stage of International Application No.

PCT/EP2004/007753, filed July 14, 2004, which claims benefit of German Application No. 103 41 986.1, filed September 9, 2003.